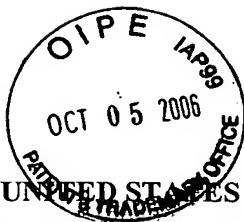


Docket No. 292378US2PCT



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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Denis HITZ, et al.

SERIAL NO: 10/582,515

GAU:

FILED: June 9, 2006

EXAMINER:

FOR: PHOTON SOURCE COMPRISING AN ECR SOURCE WITH PRESSURE GRADIENT

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97

COMMISSIONER FOR PATENTS
ALEXANDRIA, VIRGINIA 22313

SIR:

Applicant(s) wish to disclose the following information.

REFERENCES

- ☒ The applicant(s) wish to make of record the references listed on the attached form PTO-1449. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.
- ☐ A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

RELATED CASES

- ☐ Attached is a list of applicant's pending application(s), published application(s) or issued patent(s) which may be related to the present application. In accordance with the waiver of 37 CFR 1.98 dated September 21, 2004, copies of the cited pending applications are not provided. Cited published and/or issued patents, if any, are listed on the attached PTO form 1449.
- ☐ A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

CERTIFICATION

- ☐ Each item of information contained in this information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- ☐ No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

DEPOSIT ACCOUNT

- ☒ Please charge any additional fees for the papers being filed herewith and for which no check or credit card payment is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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U.S. PCT Application Serial No: 10/582,515

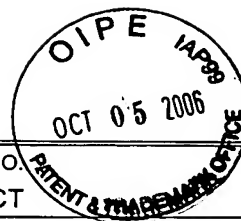
Filed: June 9, 2006

Denis HITZ, et al.

Docket No. 292378US2PCT

STATEMENT OF RELEVANCY

- 1) References have been cited in the International Search Report. A copy of these references is being submitted herewith.
- 2) References AA and AU – AW have been cited in the corresponding French Search Report. A copy of these references is being submitted herewith.
- 3) Reference AX is discussed in the specification. A copy of this reference is being submitted herewith.
- 4) References are additional prior art known to Applicant. A copy of these references is being submitted herewith.

Form PTO 1449
(Modified)U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY DOCKET NO.
292378US2PCTSERIAL NO.
10/582,515

LIST OF REFERENCES CITED BY APPLICANT

APPLICANT
Denis HITZ, et al.FILING DATE
June 9, 2006

GROUP

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA	2003 0006708	01-09-03	LEUNG, Ka-Ngo et al.			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION	
					YES	NO
	AO					
	AP					
	AQ					
	AR					
	AS					
	AT					

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)

	AU	HITZ, D. et al., "An All-Permanent Magnet ECR Ion Source for the ORNL MIRF Upgrade Project", 16 th International Workshop on ECR Ion Sources, pgs. 123-126, 2005. (With Abstract)				
	AV	HITZ, D. et al., "All-Permanent Magnet ECR Plasma for EUV Light", EUVL Symposium, 2004. (With Abstract)				
	AW	HAHTO, S. K. et al., "Permanent Magnet ECR Source for Generation of EUV Light", SEMATECH EUV Source Workshop, 2004.				
	AX	TAWARA, H. et al., "Total and Partial Ionization Cross Sections of Atoms and Ions by Electron Impact", Atomic Data and Nuclear Data Tables, Vol. 36, No. 2, pgs. 167-353, 1987. (Abstract Only)				
	AY					
	AZ					

☐ Additional References sheet(s) attached

Examiner

Date Considered

*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.